

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 241330US6YA		SERIAL NO. 10/650,729	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Chung-Peng HO, et al.			
				FILING DATE August 29, 2003		GROUP 1756	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
DP	AA 5,986,742	11/16/99	Straaijer et al.				
DP	AB 2002/0163629	11/7/02	Switkes et al.				
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION			
	AO			YES	NO		
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
DP	AW	Owen et al., "1/8 μm optical lithography," Journal of Vacuum Science and Technology, B 10(6), 3032-3036 (1992).					
DP	AX	Switkes et al., "Immersion lithography at 157 nm," Journal of Vacuum Science and Technology, B 19(6), 2353-2356 (2001).					
DP	AY	Hoffnagle et al., "Liquid immersion deep-ultraviolet interferometric lithography," Journal of Vacuum Science and Technology, B 17(6), 3305-3309 (1999).					
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner <i>Denis Schubert</i>				Date Considered 09/17/2005			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							